





Test-beam and simulation studies of the monolithic CMOS silicon sensor CLICTD

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On behalf of the CLICdp collaboration

Outline

The CLICTD sensor

Test-beam rotation studies

Simulation studies

Summary and outlook



Motivation



Objective

Development and characterisation of detector technologies for future collider experiments (e.g. the Compact Linear Collider)

- Monolithic CMOS sensors with a small collection diode
 - No interconnects, reduced material budget, profiting from CMOS imaging industry
 - Low input capacitance thanks to small collection diode

Characterisation effort



- Detailed and precise test-beam measurements and simulations required
- Corresponding flexible tools (Caribou, AIDA telescope, EUDAQ2, Corryvreckan, Allpix-Squared, TCAD...) are necessary

The project is carried out in the framework of



The strategic CERN EP R&D programme





The CLIC Tracker Detector (CLICTD)

Designed to meet the requirements of the CLIC Tracker



• Full lateral depletion in 30 µm epitaxial layer

- Channel pitch: 300 µm x 30 µm (16x128 channels)
- Collection electrode pitch: 37.5 $\mu m \ x$ 30.0 μm
- Detector channel consists of 8 sub-pixels (diode + analogue front-end)
 - Discriminator output of sub-pixels is combined in logic OR

Save space for digital circuitry while maintaining small capacitance and fast charge collection



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• MIMOSA planes

Track-position resolution at DUT: ~ 2 μ m

• Timepix3 timing plane

Timing resolution: ~ 1 ns

• AIDA TLU

Triggers MIMOSA readout and provides global time reference

See talk by Jens Kröger

- Device Under Test (DUT) CLICdp-Conf-2019-012 Readout with Caribou versatile DAQ system See talk by Eric Buschmann
- Data acquisition framework Planes are read out and controlled using EUDAQ2

EP R&D



- Reconstruction and analysis with the Corryvreckan reconstruction framework See tutorial by Jens Kröger
- CLICTD is tilted in row direction

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• Spatial resolution is best around 35 degrees where cluster size 2 is most prominent

Cluster position reconstruction is still work in progress



figure 1 Single sub-pixel f





Active depth from inclined tracks



- Complex non-uniform fields inside the sensor -> assumptions used for planar sensors do not necessarily hold
- Charge carriers below high-field depletion region can contribute to signal

- Charge carriers created within the active depth of the sensor contribute to the measured signal
- Active depth can be estimated by rotation-dependent cluster (column) size using a simple geometrical model
- Charge sharing by diffusion and threshold effects are not accounted for in this model



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Active depth from inclined tracks





- Active depth of approximately 30 μm was found for assemblies with different thicknesses (50 μm 300 $\mu m)$
- Thickness of epitaxial layer: 30 µm
- Expected depletion depth: 23 µm → Contribution from non-depleted sensor region (estimated from 3D TCAD simulations)



Monte Carlo + TCAD simulations



- 3D TCAD simulation studies for monolithic CMOS sensors are crucial to optimise sensor design
 - Simulation of e.g. capacitance, leakage current, punch-through
- Optimised sensors can be evaluated by combining electrostatic TCAD and transient Monte Carlo simulations
- Stochastic effects, fluctuations, generation of secondary particles are included in the MC simulation



https://garfieldpp.web.cern.ch/ garfieldpp



https://gitlab.cern.ch/allpixsquared/allpix-squared

See talk/tutorial by Simon Spannagel





Simulation setup



- Full detector simulation from energy deposition until digitisation of signal
- Doping profile, weighting potential and electrostatic field maps are imported from electrostatic 3D TCAD simulation to
 - ensure precise field modelling
 - allow for accurate calculation of charge carrier lifetime, drift velocities, mobilities etc.
- Transient simulation with limited lifetime of simulated charge carriers (currently not in Allpix-Squared master branch yet)



- Pixel flavour with continuous n-implant
- Detection threshold: 170 e
- Bias voltage of -6V/-6V at p-wells/substrate

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Comparison against data cluster size









Doping profiles

- What is the impact of uncertainties in the doping profiles on the charge sharing ?
- Higher lateral spread of the profile at the edge of the p-well implant (*p-well smearing*) leads to lower lateral 0.4 electric field -> higher cluster size is expected
- <u>Uncertainties in the doping profiles have</u> <u>considerable impact on cluster observables</u>





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Summary and Outlook



- CLICTD is a monolithic pixel sensor fabricated in a 180 nm CMOS imaging process
- Rotation studies were performed at the DESY II test-beam facility
 - spatial resolution of about 4 μ m (at a rotation angle of 35 degrees)
 - \bullet active depth of about 30 μm
- Simulations combining 3D TCAD and Allpix-Squared provide an accurate sensor modelling and high simulation rate
 - Precise beam telescope + flexible data analysis + simulations tools are required for a detailed assessment of the sensor performance

<u>Outlook</u>

- \bullet CLICTD samples thinned down to 40 μm are currently under investigation
- 3D TCAD plus Allpix-Squared simulations for 65 nm CMOS process
- CLICTD samples on Czochralski wafer material will be studied



The measurements leading to these results have been performed at the Test Beam Facility at DESY Hamburg (Germany), a member of the Helmholtz Association (HGF)



THE COMPACT LINEAR COLLIDER (CLIC)



- Concept for post-LHC linear electron-positron collider at CERN to be built in three energy stages (380 GeV -> 3 TeV)
- Monolithic silicon sensors are attractive candidates for large area, low-mass tracking detector foreseen for CLIC
- Requirements for tracking detector:
 - Single point resolution: 7 µm
 - Timing resolution: 5 ns
 - Material budget: ~1-2% X₀ per layer
 - Power consumption: < 150 mW/cm²







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CLICTD Tracker chip



Designed to meet the requirements of the CLIC Tracker

- Modified 180 nm CMOS imaging process with small collection diode
- Full lateral depletion in 30 µm epitaxial layer
- Optional: Gap in n-type implant in one spatial direction:
 - Speed up of charge collection





- Channel pitch: 300 μm x 30 μm (16x128 channels)
- Collection electrode pitch: 37.5 μm x 30.0 μm
- Detector channel consists of 8 sub-pixels (diode + analogue front-end) that are processed by a shared digital logic
 - Save space for digital circuitry while maintaining small capacitance and fast charge collection
- 8-bit ToA (10 ns ToA bins) + 5-bit ToT (programmable from 0.6 4.8 μs) (combined ToA/ToT for every 8 sub-pixels in 300μm dimension)
 IEEE Tran. Nucl. Sci., August 2020

doi: 10.1109/TNS.2020.3019887

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SPATIAL AND TIMING RESOLUTION

SPATIAL RESOLUTION

Eta function at 40 degree

Head-tail algorithm

$x_{\rm ht} = \frac{x_{\rm head} - x_{\rm tail}}{2} + \frac{Q_{\rm tail} - Q_{\rm head}}{2Q_{\rm avg.}}p.$

Centre–of-gravity algorithm

$$x_{\rm cog} = \frac{\sum_i Q_i x_i}{\sum_i Q_i},$$

THE ALLPIX-SQUARED FRAMEWORK

- Full detector simulation from energy deposition until digitisation of signal
- Infrastructure (core) is separated from physics (modules)
 - Simulation chain is built from individual modules (Plug & play concept)
- Static fields are imported from 3D TCAD simulations to ensure precise field modelling
- Validation of simulation with Investigator test-chip (developed within ALICE ITS upgrade)
 NIM A 964 (2020) 163784

NIM A 901 (2018) 164-172

THRESHOLD SCAN IN SIMULATION

